

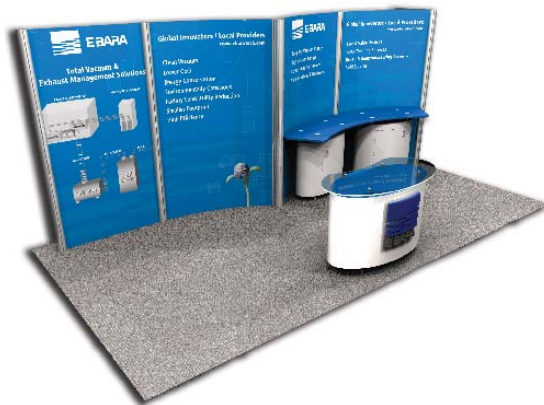


ESSENTIAL Elements

EBARA TECHNOLOGIES INC.

New & Views • July 2010 • Vol. 12 Issue 3

Come See Us at
SEMICON West



Booth # 1221 • July 13-15

Come See Us at
InterSolar North America



Booth # 8239 • July 13-15

Analog Devices Supplier Excellence Award in the category of “Local Site Support for FY2009”

Ebara Technologies, Inc (ETI) was presented an Analog Devices Supplier Excellence Award in the category of “Local Site Support for 2009 fiscal year. This award signifies Analog Devices acknowledgement of ETI’s Field service responsiveness and on site support efforts. This prestigious award comes to Ebara for the second time (ETI won Supplier Excellence Award in 2007) and reinforces the value ADI places on Component Suppliers working with them to exceed there goals.



Left to right: Mark A. Perry, Vice President and General Manager, Ebara Technologies Inc. Components Division; Geoff Ward, Manufacturing Operations Director, Analog Devices Wilmington, MA; Jason Stokes, On Site Field Service Representative, Ebara Technologies Inc, Components Division; Randy Clavet, Eastern Region Field Service Manager, Ebara Technologies Inc, Components Division; Jack Dillon, Equipment Engineer Manager, Analog Devices Inc; Vince Simonelli, Purchasing Manager, Analog Devices, Inc.



The New Green is EBARA Blue. Global Service/Local Providers

Novell Perfluorocarbons (PFC) Abatement Produces Zero Waste

EBARA's FDS Systems (Fluorine Dry Scrubber) are capable to abate most PFC gases > 99.9%. The technology utilizes a heated proprietary catalyst that both destructs and captures the fluorine compound for ultimate PFC gas treatment. The FDS Systems do not require any special fuels or water to abate the PFCs resulting in low facility requirements and zero waste water generated. Perfect for facilities that have to reduce their PFC gas but lack the infrastructure to support combustion-wash and catalytic-wash technologies.



EBARA offers three models, FDS100, FDS100D and FDS250. The FDS100 is sized for 100 liter per minute inlet gas flow and FDS250 is sized for 250 liter per minute inlet gas flows. The FDS100D and FDS250 have two reactor canisters with serial flow allowing for 100% uptime for abating the gases. FDS Systems can abate PFCs over 99.9% without producing other harmful by-products like NOx, SOx and hazardous solid wastes. The exhausted reagents are not hazardous and can be recycled and used as raw materials for other industrial processes resulting in zero total waste.



EBARA Technologies, Inc.
Service and Sales presence:

Headquarters
51 Main Ave.
Sacramento, CA 95838
1-800-535-5376

San Jose, CA	Newburyport, MA
Portland, OR	South Portland, MA
Manassas, VA	East Fishkill, NY
Austin, TX	Essex Junction, NY
Wake Forest, NC	Yorktown, NY

EBARA High Vacuum Pumping System

EBARA Technologies, Inc introduces High Vacuum Pumping System (HVPS). The HVPS is a customizable and flexible pumping station that is both reliable and cost-effective method of producing high vacuum.

The HVPS is a closed configured system with integrated power management and controls systems allowing for plug-and-play installation. The HVPS can integrate optional low and high vacuum gauges for totally dry vacuum system for applications delivering dependable, ultraclean vacuum. The High Vacuum Pump System can be configured with ceramic bearing or magnetic levitated bearing turbo pumps backed by dry vacuum pumps.

Available in both a bench top version and a portable cart system, the HVPS will pump from 70 to 1300 liters per second with an ultimate pressure up to 7.5×10^{-9} Torr.

Some applications are:

- UHV systems
- Research & Development
- Beam lines
- Load locks
- Surface science
- High energy physics
- Leak Detection Systems
- Vacuum process technologies



Come See Us at:

2010 Semicon West
San Francisco, CA
July 13-15, 2010

2010 InterSolar North America
San Francisco, CA
July 13-15, 2010

2010 Rocky Mountain AVS
Denver, CO
September 15, 2010



www.ebaratech.com
1-800-535-5376